' Sheet'1 of 1 INFORMATION DISCLOSURE ATTY, DOCKET NO. SERIAL NO. **CITATION** 249-245 Unknown **APPLICANT** TOMONARI et al. (Use several sheets if necessary) FILING DATE GROUP January 24, 2002 2834 U.S. PATENT DOCUMENTS *EXAMINER INITIAL DOCUMENT NUMBER FILING DATE DATE NAME SUBCLASS CLASS IF APPROPRIATE 5,058,856 10/1991 GORDON et al. 5,069,419 12/1991 **JERMAN** 5,271,597 12/1993 **JERMAN** 5,059,133 10/1991 HIKAMI et al. 5,870,007 2/1999 CARR et al. 5,920,417 7/1999 JOHNSON 6,044,646 4/2000 SILVERBROOK 6,114,794 9/2000 DHULER et al. 1,258,368 3/1918 **SMITH** 4,115,750 9/1978 HANSEN et al. 6,087,638 7/2000 SILVERBROOK 6,124,663 9/2000 HAAKE et al. FOREIGN PATENT DOCUMENTS TRANSLATION DOCUMENT DATE COUNTRY **CLASS SUBCLASS** YES NO 9-88805 3/1997 **JAPAN** 10-173306 6/1998 **JAPAN** OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.) "Silicon Microvalves for Gas Flow Control" Phillip W. Barth, Ph.D. Hewlett-Packard Laboratoriespp 276-279 The 8th International Conference on Solid-State Sensors and Actuators, and Eurosensors IX. Stockholm, Sweden, June 25-29, 1995 "Electrically-Activated, Micromachined Diaphragm Valves" Hal Jerman IC Sensors Milpitas, CA 95035 pp 363-367

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.

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